P27139.A03

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kangguo CHENG

Group Art Unit: 2812

Serial No:10/710,608

Examiner: Bradley SMITH

Filed: July 23, 2004

For: PATTERNED STRAINED SEMICONDUCTOR SUBSTRATE AND DEVICE

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria VA 22314

Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and supplemental to the Information Disclosure Statement filed on July 23, 2004 and August 23, 2005, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application.

Further to the U.S. Patent and Trademark Office's decision to waive the requirement under 37 C.F.R. § 1.98 (a)(2)(i), copies of the U.S. patents and U.S. published patent applications are not enclosed herewith. However, if any copies are needed, the Examiner is respectfully requested to contact the undersigned.

Applicant respectfully requests that the Examiner consider the materials cited and indicate such consideration by appropriately initialing the enclosed PTO-1449 Form and including a copy of the initialed form in the next official communication.

## P27139.A03

Should there be any questions concerning this application, the Examiner is invited to contact the undersigned at the below listed telephone number.

Respectfully submitted, Kangguo CHENG

Andrew M. Calderon Reg. No.:38,093

GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191

## Application No. Atty. Docket No. U.S. Department of Commerce FORM PTO-1449 10/710,608 Patent and Trademark Office Applicant INFORMATION DISCLOSURE STATEMENT Kangguo CHENG et al. BY APPLICANT (Use several sheets if necessary) Filing Date Group 2812 07/23/2004 U.S. PATENT DOCUMENTS FILING DATE **EXAMINER** IF APPROPRIATE **CLASS SUBCLASS** DOCUMENT NUMBER DATE NAME INITIAL US 2002/0063292 A1 5-30-2002 Armstrong et al. Yeh et al. US 2003/0032261 A1 2-13-2003 2-27-2003 Saitoh US 2003/0040158 A1 12-2-2004 Deshpande et al. US 2004/0238914 A1 12-30-2004 Doris et al. US 2004/0262784 A1 Chidambarrao et al. US 2005/0040460 A1 2-24-2005 Doris et al. 4-21-2005 US 2005/0082634 A1 5-5-2005 Doris et al. US 2005/0093030 A1 Doris et al. 5-12-2005 US 2005/0098829 A1 5-19-2005 Doris et al. US 2005/0106799 A1 Zhu et al. 7-7-2005 US 2005/0145954 A1 7-7-2005 Doris et al. US 2005/0148146 A1 9-8-2005 Belyansky et al. US 2005/0194699 A1 US 2005/0236668 A1 10-27-2005 Zhu et al. US 2005/0245017 A1 Belvansky et al. 11-3-2005 Chidambarrao et al. 12-22-2005 US 2005/0280051 A1 Belyansky et al. US 2005/0282325 A1 12-22-2005 US 2006/0027868 A1 2-9-2006 Doris et al. 3-16-2006 Doris et al. US 2006/0057787 A1 US 2006/0060925 A1 3-23-2006 Doris et al. Forbes et al. 11-19-2002 6,483,171 Currie et al. 12-14-2004 6,831,292 4-6-2004 Doris et al. 6,717,216 Chidambarrao et al. 11-30-2004 6,825,529 Doris et al. 7,015,082 3-21-2006 12-13-2005 Chidambarrao et al. 6,974,981 Belyansky et al. 12-20-2005 6,977,194 FOREIGN PATENT DOCUMENTS TRANSLATION DATE COUNTRY CLASS **SUBCLASS** YES DOCUMENT NUMBER Х 3-22-1989 Japan JP 64-76755 OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**EXAMINER** 

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	OTHER DOCUME	NTS (Including Autho	r, Titl	e, Date, Pertinent	Pages, Etc.)				
	G. Zhang, et al., "A New 'M Bipolar Transistors." IEEE 7	ixed-Mode' Reliab Fransactions on Ele	oility ectror	Degradation M Devices, vol. 4	echanism 19, no. 12,	in Adv Decei	vanced Si mber 2002	and SiGe 2, pp. 2151-5	6.
	H.S. Momose, et al., "Temperature Dependence of Emitter-Base Reverse Stress Degradation and its Mechanism Analyzed by MOS Structures." 1989 IEEE, Paper 6.2, pp. 140-143.								
	C.J. Huang, et al., "Temperature Dependence and Post-Stress Recovery of Hot Electron Degradation Effects in Bipolar Transistors." IEEE 1991, Bipolar Circuits and Technology Meeting 7.5, pp. 170-173.								
100,000	S.R. Sheng, et al., "Degradation and Recovery of SiGe HBTs Following Radiation and Hot-Carrier Stressing." pp. 14-15.								
	Z. Yang, et al., "Avalanche Current Induced Hot Carrier Degradation in 200 GHz SiGe Heterojunction Bipolar Transistors." pp. 1-5.								
	H. Li, et al., "Design of W-E Automotive Radar Systems."	Band VCOs with H " 2003, IEEE GaA	igh C s Dig	output Power fo est, pp. 263-66	r Potentia	l Appl	ication in	77 GHz	
	H. Wurzer, et al., "Annealin on Electron Devices, vol. 41	g of Degraded non , no. 4, April 1994	-Trar , pp.	sistors-Mechan 533-38.	isms and	Model	ing." IEE	E Transactio	ns
	B. Doyle, et al., "Recovery of Device Letters, vol. 13, no.				litrided O	xide M	1OSFETs.	." IEEE Elect	ron
	H.S. Momose, et al. "Analys Bipolar Transistors for Bi-C 978-987.	sis of the Temperat MOS." IEEE Tran	ure E sactio	Dependence of I ons on Electron	fot-Carrie Devices,	r-Indu vol. 41	ced Degra I, no. 6, Ju	adation in une 1994, pp.	
	M. Khater, et al., "SiGe HBT Technology with Fmax/Ft = 350/300 GHz and Gate Delay Below 3.3 ps". 2004 IEEE, 4 pages.								ps".
	J.C. Bean, et al., "GEx SI 1-x/Si Strained-Layer Superlattice Grown by Molecular Beam Epitaxy". J. Vac. Sci. Technol. A 2(2), AprJune 1984, pp. 436-440.								<b>:.</b>
	J.H. Van Der Merwe, "Regular Articles". Journal of Applied Physics, Volume 34, No. 1, January 1963, pp. 117-122.								р.
	J.W. Matthews, et al., "Defe	J.W. Matthews, et al., "Defects in Epitaxial Multilayers". Journal of Crystal Growth 27 (1974), pp. 118-125.							
	Subramanian S. Iyer, et al. " Electron Devices, Vol. 36, 1	Heterojuction Bip	olar 89, p	Transistors Usi p. 2043-2064	ng Si-Ge A	Alloys'	". IEEE T	ransactions o	n
	R.H.M. Van De Leur, et al., Superlattices". J. Appl. Phys	"Critical Thickness. 64 (6), 15 Septer	s for nber	Pseudomorphio 1988, pp. 3043	Growth (	of Si/C	Ge Alloys	and	
	D.C. Houghton, et al., "Equ	ilibrium Critical Tl	hickn	ess for SI 1-x C	Ex Strain	ed Lay	ers on (1	00) Si". Appl	l.

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Q. Quyang et al., "Two-Dimensional Bandgap Engineering in a Novel Si/SiGe pMOSFET with Enhanced

DATE CONSIDERED

Phys. Lett. 56 (5), 29 January 1990, pp. 460-462

**EXAMINER** 

Device Performance and Scalability". 2000, IEEE, pp. 151-154.